

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Gregory Michael Wilson et al.

Art Unit 1765

Serial No. 09/608,302 Filed June 30, 2000 Confirmation No. 9819

A METHOD AND APPARATUS FOR FORMING A SILICON WAFER WITH A

DENUDED ZONE

Examiner Robert M. Kunemund

April 21, 2003

AMENDMENT C AND RESPONSE AFTER RCE

TO THE ASSISTANT COMMISSIONER FOR PATENTS,

SIR:

In response to the Office action dated December 19, 2002, please make the following amendments, which are submitted in accordance with the proposed format revisions to 37 CFR 1.121, and consider the following remarks and arguments set in this Amendment C and Response filed with a Request For Continued Examination:

w/druge

